

Effect of α -(Al_xGa_{1-x})₂O₃ Overgrowth on MSM-Type α -Ga₂O₃ Ultraviolet Photodetectors Grown by Mist CVD

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Ultraviolet (UV) photodetectors using high Al content AlGaN have been studying towards applications such as flame detection, sterilization and so on [1]. However, the growth of high-quality AlGaN with increased Al content required for UV photodetector has difficulty in epitaxy. Therefore, we have been focusing on corundum-structured gallium oxide (α -Ga₂O₃) as an alternative material. α -Ga₂O₃ has a wide bandgap of 5.3 eV, and the bandgap engineering is possible in whole composition range of (Al, Ga, In)₂O₃ alloys [2, 3]. Moreover, they can be heteroepitaxially grown on a variety of corundum-structured oxide materials, i.g., α -Cr₂O₃, α -Fe₂O₃, etc. A β -Ga₂O₃ based UV photodetector has been shown to have high responsivity [4], and Al₂O₃ deposition on β -Ga₂O₃ for surface passivation has been reported [5]. In contrast, α -Ga₂O₃ detector has so far not yet been reported.

In this study, a metal-semiconductor-metal (MSM)-type UV photodetector using α -(Al_xGa_{1-x})₂O₃ on α -Ga₂O₃ is fabricated by mist CVD.

1- μ m-thick unintentionally doped α -Ga₂O₃ film was grown on *c-plane* sapphire substrate by mist CVD. Ga acetylacetonate was used as a source material for this mist CVD growth, and it was solved in deionized water with a small amount of hydrochloric acid. The concentration of Ga was 0.05 mol/L. It was followed by 20-50-nm-thick (Al_xGa_{1-x})₂O₃ growth using Al and Ga acetylacetonate as source materials. Then, α -Ga₂O₃-based MSM-type photodetector was fabricated by employing Ni (50 nm)/Au (100 nm) pads as Schottky electrodes.

Figure 1 shows XRD 2θ - ω scan profile. (0006) α -Al₂O₃ and (0006) α -Ga₂O₃ diffraction peaks were observed. 2θ - ω and ϕ scan profiles indicate growth of single crystalline epitaxial film. As shown in Fig. 2, the full-width at half maximum of the X-ray rocking curve for (0006) α -Ga₂O₃ diffraction peak is 39.8 arcsec. The absorption coefficient α was determined by optical transmittance measurements. Then, $(\alpha h\nu)^2$ - $h\nu$ plots give bandgap energy of 5.3 eV. Figure 3 shows photo-responsivity of the MSM-type photodetector. Increase in responsivity above the bandgap energy of 5.3 eV was successfully observed. Maximum photo-responsivity was estimated to be 1.0 A/W. However, the photo-responsivity decreased in the energy range between 5.6 and 5.8 eV due to surface effect of the α -Ga₂O₃ film. Surface effect on MSM-type UV photodetectors using α -(Al_xGa_{1-x})₂O₃ on α -Ga₂O₃ structure will be shown at the conference.

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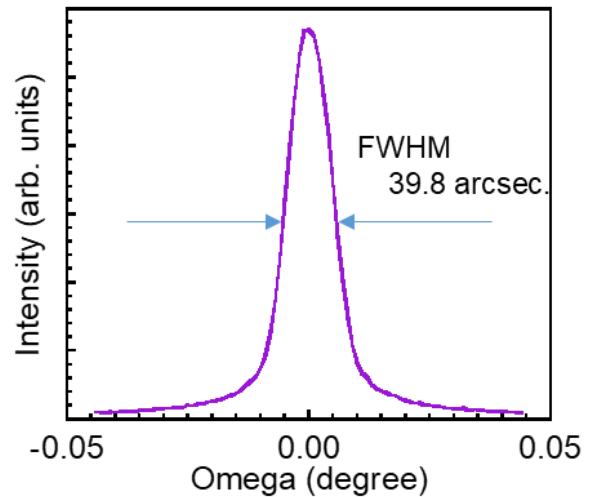
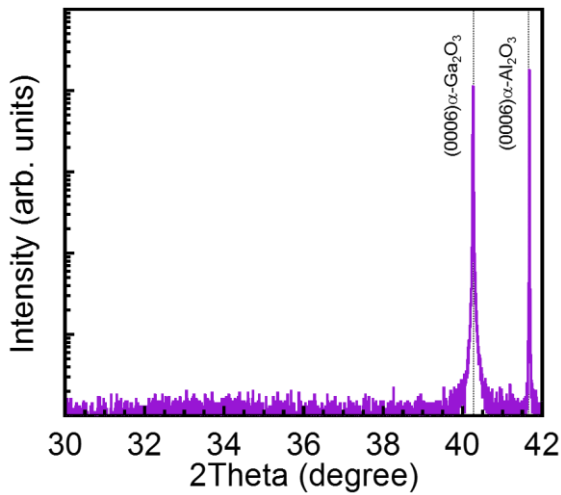


Fig. 1: XRD 2θ-ω scan profile of Ga₂O₃ film.

Fig. 2: XRD ω scan profile of Ga₂O₃ film.

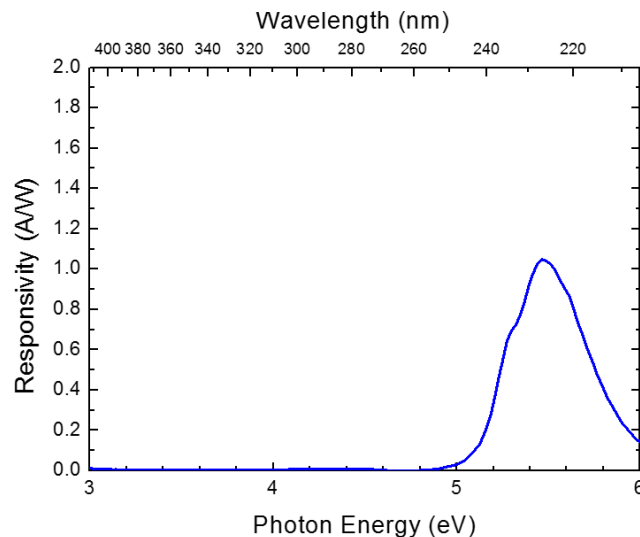


Fig. 3: Photoresponsivity spectrum at room temperature in MSM-type photodetector fabricated using α-Ga₂O₃ film.